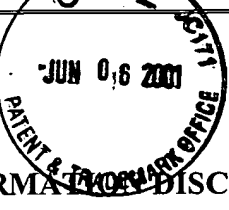


FACSIMILE OF FORM PTO-1449 (REV. 6-89)		 U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office		ATTORNEY'S DOCKET NUMBER <b>97RSS519</b>		SERIAL NUMBER <b>09/676,998</b>	
<b>INFORMATIONAL DISCLOSURE CITATION</b> (Use Several Sheets if Necessary)				APPLICANTS <b>Joshua I. Pine</b>		FILING DATE <b>September 29, 2000</b>	
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U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS							
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
					YES	NO	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
<i>YGA</i>	"TI Demonstrates Digital Micromirror Devices (DMD) Technology: News Releases," ( <a href="http://www.ti.com/corp/docs/press/company/1994/405asc.shtml">http://www.ti.com/corp/docs/press/company/1994/405asc.shtml</a> ), © 2000, Texas Instruments, Inc., pp. 1-4. (downloaded on 4/18/00)
<i>YGA</i>	"Digital Micromirror Device Delivering on Promises of "Brighter" Future for Imaging Applications," ( <a href="http://www.ti.com/corp/docs/company/history/dmd.shtml">http://www.ti.com/corp/docs/company/history/dmd.shtml</a> ), © 2000, Texas Instruments, Inc., pp. 1-6. (downloaded on 4/18/00)
<i>YGA</i>	"The State of the Art in Projection Display: An Introduction to the Digital Light Processing (DLP) Technology," Lars A. Yoder, ( <a href="http://www.ti.com/corp/dlp/resources/whitepapers/overview/state.shtml">http://www.ti.com/corp/dlp/resources/whitepapers/overview/state.shtml</a> ), © 1999, Texas Instruments, Inc., pp. 1-5. (downloaded on 4/18/00)
<i>YGA</i>	"About MEMS," ( <a href="http://mems.sandia.gov/">http://mems.sandia.gov/</a> ), Sandia National Laboratories: Intelligent Micromachine Initiative, p. 1. (downloaded on 4/18/00)
<i>YGA</i>	"DLP", A Texas Instruments Technology: "DLP" and Digital Display Interfaces: The Complete Digital Solution," Marc Pyne and Lars Yoder, Jun. 10, 1999, pp. 1-8.

EXAMINER <i>YGA</i>	DATE CONSIDERED <i>02/17/04</i>
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the patent owner.	